

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  
Trung T. Doan

Serial No.:

Filed: August 14, 1998

Title: CHEMICAL DISPENSING SYSTEM FOR  
SEMICONDUCTOR WAFER PROCESSING

§  
§ Group Art Unit:  
§  
§ Examiner:  
§  
§  
§ Atty. Docket: 93-0421.03  
§  
§  
§  
§

August 14, 1998

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

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*[Signature]*  
Signature

Dear Sir:

The application filed herewith is a continuation of application serial # 08/944,135, which is a file wrapper continuation of application serial # 08/618,072. After awarding this application the priority filing date of the original application (serial # 08/618,072) filed February 27, 1996, please amend the current application as follows.